## Electronic structure of molybdenum oxide oxidized at different pressures

© P.A. Dementev<sup>1</sup>, E.V. Ivanova<sup>1</sup>, M.N. Lapushkin<sup>1</sup>, D.A. Smirnov<sup>2</sup>, S.N. Timoshnev<sup>3</sup>

<sup>1</sup> loffe Institute,
194021 St. Petersburg, 194021 Russia
<sup>2</sup> Institut für Festkörper- und Materialphysik, Technische Universität Dresden,
01062 Dresden, Germany
<sup>3</sup> Alferov University,
194021 St. Petersburg, 194021 Russia

E-mail: demenp@yandex.ru, ivanova@mail.ioffe.ru, lapushkin@ms.ioffe.ru, wnmw@ya.ru, timoshnev@mail.ru

Received June 23, 2020 Revised July 23, 2020 Accepted for publication July 27, 2020

Electronic structure of molybdenum oxides obtained by the oxidation of molybdenum at an oxygen pressure of 1 Torr (thin film) and air (thick film) was studied. It was shown that a thick oxide film is formed from  $MoO_3$  oxide, and a thin film from a mixture of  $MoO_3$  and  $MoO_2$  oxides, which is reflected in the form of valence band spectra. Oxygen on the surface belongs both in molybdenum oxide and in the hydroxyl group, which is associated with dissociative adsorption of water during the oxidation of molybdenum in air for a thick film.

Keywords: molybdenum oxide, oxidation, valence band, photoelectron spectroscopy.

Full text of the paper will appear in journal SEMICONDUCTORS.